

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kenichi SHIRAI SHI

Application No.: New U.S. National Phase of PCT/JP2005/001827

Filed: August 1, 2006

Docket No.: 128985

For: EXPOSURE APPARATUS, DEVICE MANUFACTURING METHOD, MAINTENANCE METHOD, AND EXPOSURE METHOD

INFORMATION DISCLOSURE STATEMENT

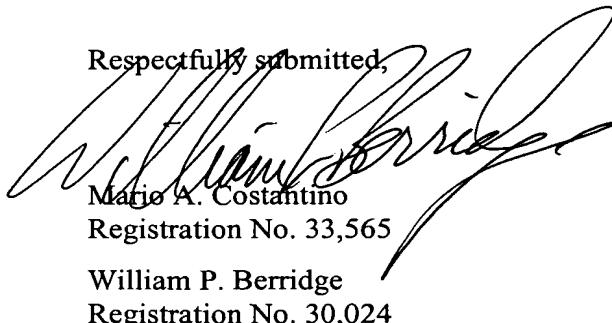
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- 2. Relevance of one or more non-English language reference is discussed in the present specification. See Reference 2.
- 3. One or more reference cited herein was cited in the International Search Report. An English language version of the International Search Report is attached for the Examiner's information. See References 1-6.
- 4. An English language Abstract of one or more non-English language reference is attached hereto. See References 1-6.
- 5. A computer-generated English language translation of one or more Japanese Patent Publication cited herein has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 1, 3 & 6.

Respectfully submitted,



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<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
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Form PTO-1449 (REV. 1/06)			US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 128985	APPLICATION NO. New U.S. National Phase of PCT/JP2005/001827 10/588146	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)			APPLICANT Kenichi SHIRAISHI			
			FILING DATE August 1, 2006			
U.S. PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Name		
FOREIGN PATENT DOCUMENTS						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
	1.	JP-A-2000-058436	02/25/2000	JAPAN	X	X
	2.	WO 99/49504 A1	09/30/1999	WIPO	X	
	3.	JP-A-10-303114	11/13/1998	JAPAN	X	X
	4.	WO 2004/105107 A1	12/02/2004	WIPO	X	
	5.	WO 2005/020299 A1	03/03/2005	WIPO	X	
	6.	JP-A-2005-064210	03/10/2005	JAPAN	X	X
OTHER DOCUMENTS						
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)				
EXAMINER					DATE CONSIDERED	
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						